

PATENT
0796/71238

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Mark Hornung, et al.
Serial No. : Not Yet Known
Filing Date : Herewith
For : DEVICE AND METHOD FOR MEASURING THE FLOW AND
AT LEAST ONE MATERIAL PARAMETER OF A FLUID

Priority Date
Claimed : November 27, 2002
Group A.U. : Not Yet Known
Examiner : Not Yet Known

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October 17, 2003

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

As a means of complying with the duty of disclosure set forth in 37 CFR 1.56 and in keeping with the guidelines of 37 CFR 1.98, Applicants hereby submit information thought to be relevant to the above-identified application. Also submitted herewith is a completed form PTO-1449. The cited documents are:

US 2003/0115952	June 26, 2003
US 6,460,411	October 8, 2002
US 6,349,596	February 26, 2002
US 6,209,402	April 3, 2001
US 5,830,372	November 3, 1998
US 5,804,720	September 8, 1998
US 5,596,219	January 21, 1997
US 5,533,412	July 9, 1996
US 5,406,841	April 18, 1995
US 5,339,687	August 23, 1994

US 4,909,078	March 20, 1990
US 4,501,145	February 26, 1985
US 4,373,386	February 15, 1983
WO 01/81872	November 1, 2001
WO 01/18500	March 15, 2001
WO 01/98736	December 27, 2001
DE 101 29 300	June 18, 2001
DE 199 60 538	July 6, 2000
EP 1 065 475	May 12, 2000
EP 0 484 645	August 30, 1991

F. Cascetta et al., "The future domestic gas meter: Review of current developments", 8252 Measurement, 13(1994) April, No. 2, pp. 129-145;

M. Ashauer et al., "Thermal flow sensor for Liquids and Gases", Proc. IEEE. 98CH36176, pp. 351-355;

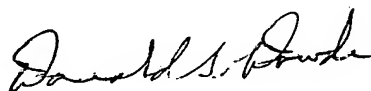
F. Mayer et al., "Scaling of Thermal CMOS Gas Flow Microsensors: Experiment and Simulation", Proc. IEEE. 96CH35856, pp. 116-121.

These documents are listed on the attached from PTO-1449, and a copy of each is enclosed. It is requested that the Examiner enter the cited documents in the file of the application and consider them under Rule 56.

Favorable action is respectfully solicited.

No fee is believed to be due. However, the Patent Office is authorized to charge any fee or credit any overpayment to our deposit account No. 03-3125. A copy of this sheet is enclosed.

Respectfully submitted,
COOPER & DUNHAM LLP



Donald S. Dowden
Reg. No. 20,701

Form PTO-1449		U.S. Department of Commerce Patent and Trademark Office				Atty. Docket No. 7284/41926-CIP		Serial No. 09/414,043							
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)						Applicants James M. Janky et al.									
						Filing Date 02/09/99		Group							
U.S. PATENT DOCUMENTS															
Examiner Initial			Document Number					Date	Name	Class	Subclass	Filing Date if Appropriate			
		2003	0	1	1	5	9	5	2	06/26/03	Mayer et al.	73	204.26		
			6	4	6	0	4	1	1	10/08/02	Kersjes et al.	73	204.26		
			6	3	4	9	5	9	6	02/26/02	Nakada et al.	73	204.26		
			6	2	0	9	4	0	2	04/03/01	Yamada	73	861.26		
			5	8	3	0	3	7	2	11/03/98	Hierold	216	2		
			5	8	0	4	7	2	0	09/08/98	Morimasa et al.	73	204.26		
			5	5	9	6	2	1	9	01/21/97	Hierold	257	467		
			5	5	3	3	4	1	2	07/09/96	Jerman et al.	73	861.95		
			5	4	0	6	8	4	1	04/18/95	Kimura	73	204.26		
			5	3	3	9	6	8	7	08/23/94	Gimson et al.	73	204.19		
			4	9	0	9	0	7	8	03/20/90	Sittler et al.	73	204.26		
			4	5	0	1	1	4	5	02/26/85	Boegli et al.	73	204		
			4	3	7	3	3	8	6	02/15/83	Schuddemat et al.	73	189		
FOREIGN PATENT DOCUMENTS															
			Document Number					Date	Country	Class	Subclass	Translation			
													Yes	No	
		WO	0	1	8	1	8	7	2	11/01/01	PCT	GO1F	1/684		X
		WO	0	1	1	8	5	0	0	03/15/01	PCT	GO1F	1/664	partial	
		WO	0	1	9	8	7	3	6	12/27/01	PCT	GO1F	1/684	partial	
		DE	10	1	2	9	3	0	0	02/07/02	Germany	GO1F	5/00	partial	
		DE	19	9	6	0	5	3	8	07/06/00	Germany	GO1F	1/692		X
		EP	1	0	6	5	4	7	5	01/03/01	Europe	GO1F	1/68	X	
		EP	0	4	8	4	6	4	5	05/13/92	Europe	GO1F	1/68		
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)															
		F. Cascetta et al., 'The future domestic gas meter: Review of current developments', 8252 Measurement, 13(1994) April, No. 2, pp. 129-145;													
		M. Ashauer et al., 'Thermal flow sensor for Liquids and Gases', Proc. IEEE. 98CH36176, pp. 351-355;													
		F. Mayer et al., 'Scaling of Thermal CMOS Gas Flow Microsensors: Experiment and Simulation', Proc. IEEE. 96CH35856, pp. 116-121.													
EXAMINER										DATE CONSIDERED					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this from with next communication to applicant.															